

AND LIQUID DISCHARGE RECORDING HEAD, AND METHOD OF MANUFACTURE

PATENT APPLICATION

October 31, 2001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

KIYOTAKA WASA ET AL.

Application No.: 09/880,757

Filed: June 15, 2001

For: STRUCTURE OF PIEZOELECTRIC ELEMENT

PARTICLE STRUCTURE OF PIEZOELECTRIC ELEMENT

PARTICLE STRUCTURE OF PIEZOELECTRIC ELEMENT

Commissioner for Patents Washington, D.C. 20231

THEREOF

INFORMATION DISCLOSURE STATEMENT

Sir:

35.C15462

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

Among the listed documents, the Japanese article, "Sputtering Technologies", is discussed in the specification at page 4, and the Examiner is directed thereto for the concise explanation of relevance of this non-English document. The other listed documents were cited in an August 31, 2001 European search report, a copy of which is also enclosed.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

Attorney for Applicants

Registration No. 79 46

FITZPATRICK, CELLA, HARPER & SCINTO 30 Rockefeller Plaza New York, New York 10112-3801

Facsimile: (212) 218-2200